

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE****IN THE MATTER OF:**

Jaehwan EUN, et al

ART UNIT: 1792

SERIAL NO.: 10/539,883

EXAMINER: Kunemund, Robert M.

FILED: June 17, 2005

CONFIRMATION NO.: 1957

FOR: Method For Preparation of Ferroelectric Single Crystal Film Structure Using  
Deposition Method**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Arlington, VA 22313-1450

SIR:

This is in response to the outstanding Office Communication dated November 14, 2007. The Commissioner is authorized to charge any fees required in the prosecution of this application to Deposit Account No. 503814.

Please amend the present application as follows: